

ABSTRACT

Electromechanical microstructure 1 comprising a
5 first part known as the mechanical part 102 formed in a
first electrically conductive material, and which
comprises on the one hand a zone deformable in an
elastic manner 104 having a thickness value and an
exposed surface 2, and on the other hand a first organic
10 film 4 having a thickness, present on all of the exposed
surface 2 of said deformable zone 104, characterised in
that the thickness of the first film 4 is such that the
elastic response of the deformable zone 104 equipped
with the first film 4 does not change by more than 5%
15 compared to the response of the bare deformable zone 104
or in that the thickness of the first film 4 is less
than ten times the thickness of the deformable zone 104.

Application to the manufacture of
electromechanical microstructures.

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Figure 3a